

Supporting Information

Time-Evolution of the Electrical Characteristics of MoS₂ Field Effect Transistors After Electron Beam Irradiation

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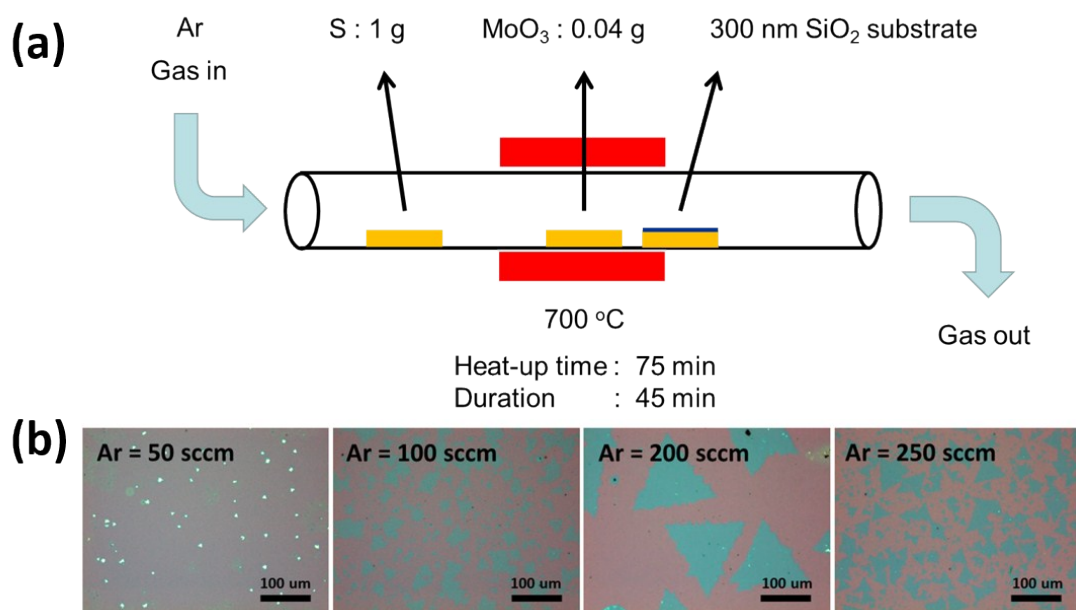


Figure S1 (a) Schematic representation of the setup for CVD growth of MoS₂ flakes. (b) OM images of MoS₂ flakes obtained at various Ar carrier gas flow rates.

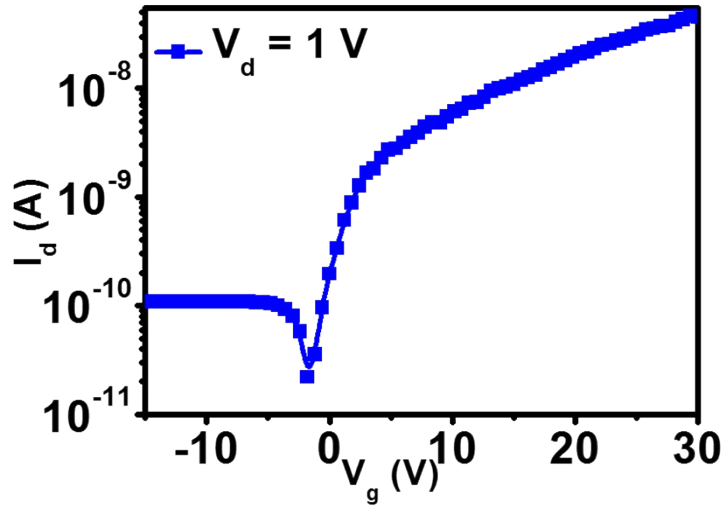


Figure S2 Transfer characteristic of a non-irradiated MoS₂ FET, measured at a value of V_d of 1 V, plotted on a logarithmic scale.

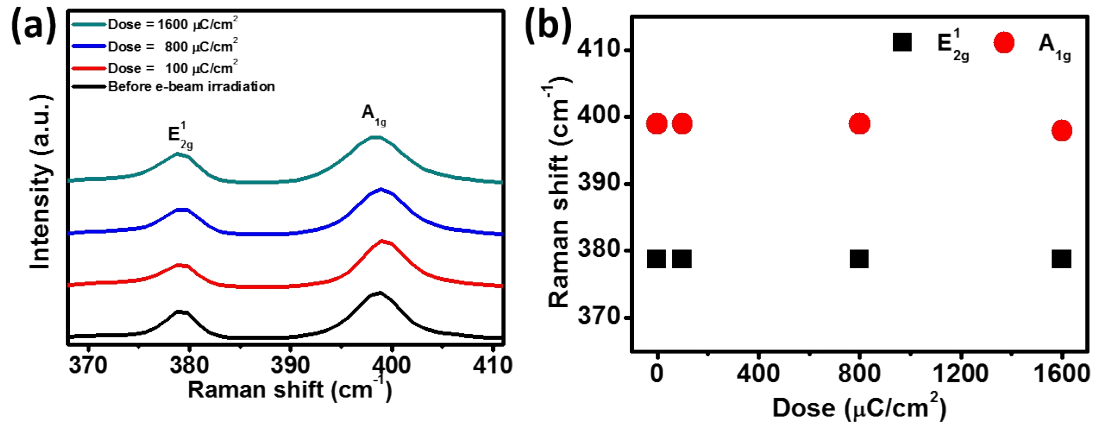


Figure S3 (a) Raman spectra of MoS₂ recorded before and after e-beam irradiation at various doses. (b) Positions of the E_{2g}^1 and A_{1g} vibration modes of MoS₂ after e-beam irradiation at various doses; the positions are almost identical, indicating that the MoS₂ did not undergo any significant structural change.

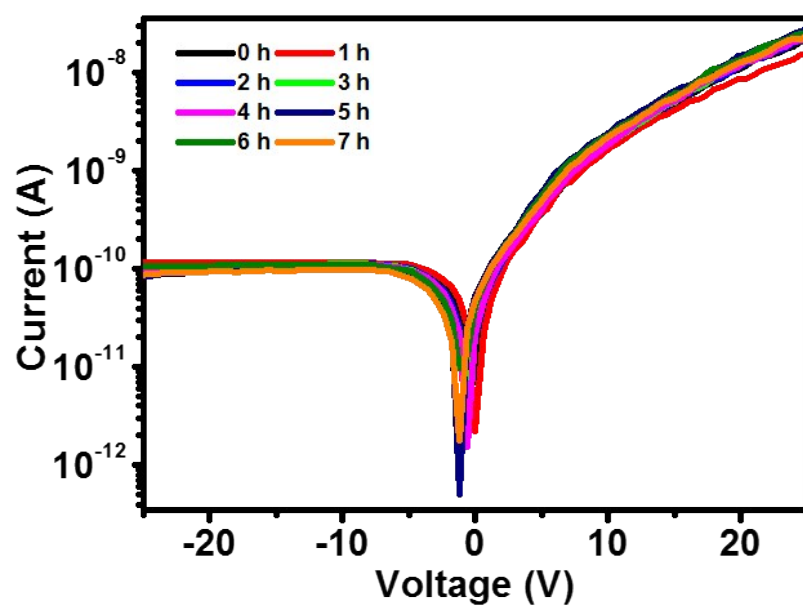


Figure S4 Transfer characteristics of a non-irradiated MoS₂ FET, measured after various periods of time.